

MICROELECTROMECHANICAL DEVICE AND METHOD FOR PRODUCING IT

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Abstract

~~The invention relates to a~~ microelectromechanical device and a method for producing it having at least one layer on a substrate, in particular a thermoelectric layer on a substrate, the thermal expansion coefficient of the at least one layer and the thermal expansion coefficient of the substrate differing greatly. ~~The invention provides for a~~The at least one layer (1) ~~to be~~is coupled to at least one stress reduction means (2) for the targeted reduction of lateral mechanical stresses present in the layer (1). This achieves a stress-free layer or enables stress-free growth.